

General Information

Maker
Model
Process
Platform Type

Vintage

Selected Option

AMAT
Centura EPI
EPI RP
ACP Frame

Remark
Wafer Specification

Wafer Size

Selected Option

300MM (12 INCH)

FI (Front Interface module)

FI Frame
Robot
Pre-aligner
Controller
Server
UPS
Load Port

Selected Option

ACP 5.3 Factory Interface
Yaskawa XU-RC350S-J01
Yaskawa XU-ACP130-A14
Yaskawa ERCR-NS01-B004-E1
AMAT CGA Server (FES / FIS / RTS)
Eaton Powerware UPS 5115 1U Rackmount 208VAC
Sinfonia SELOP12F25-S7A0020

TM (Main Frame Transfer Module)

Main frame
TM Controller
Robot
Robot driver
Actuator assy
Motion controller

Selected Option

ACP Mainframe
Ethernet / TM Interlock / Loadlock Interface
VHP-E CR Cooled, SBR
NSK ELA-B014CG2-04
Parker ACP Slit Valve Pneumatic Cylinder Series P1D
AMAT 8 AXIS MOTION CONTROLLER T008-2001

Chamber Type / Location

Position A
Position C
Position

Selected Option

EPI RP
EPI RP
SiCoNi

(A/C) - EPI RP
EPI RP Chamber

Rotation assy

Selected Option

Yaskawa AC Servo motor SGMMPH-01AAE-YA34

(N/A) - SiCoNi
SiCoNi Chamber

Watlow controller
Bakeout Heater driver
Lift motor
Lift Assy

Selected Option

StepSyn 103F7851-74X942
Rexroth HTR CVD PSK90 MACH

SYSTEM Rack

Chamber controller
Chamber controller
System controller
Servopack driver

Aera PI-98 Series
EPI / CH-A
EPI / CH-C
Wafer leak detector / Gas detector
Yaskawa SGDS-01A31A

Main AC

EATON LD 35k (600A)
EATON FD 35k
EATON FDB 14k
EATON J250E
Model P1191D

Sub AC
SCR Lamp driver